

the intermediate table comprising a major surface provided with a plurality of apertures, and a gas bearing generator constructed and arranged to generate a gas bearing between said major surface and a substrate located thereon;

a first temperature controller constructed and arranged to regulate a temperature of the intermediate table; and

an ionizer constructed and arranged to ionize the gas.

21. (Amended) A substrate preparing device according to claim 12,

wherein said first temperature controller maintains the intermediate table and the gas bearing at a temperature substantially equal to a temperature of the substrate table.

*See the attached Appendix for the changes made to effect the above claim(s)*